

ABSTRACT OF THE DISCLOSURE

A susceptor for use in a Czochralski crystal growing apparatus is disclosed wherein erosion of the susceptor is minimized. The susceptor contains ventilation holes that allow process gases found between the susceptor and crucible to escape. The crucible may incorporate the use of a protective coating over part or all of the susceptor, such as a silicon carbide coating. The ventilation holes are placed at various heights along the susceptor wall to allow ventilation near the area of plastic deformation of the crucible.